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Amendments to the Claims:

This listing of claims will replace all prior versions, and listings of claims in the application:

Listing of Claims:

Claim 1 (currently amended): A <u>single-gated</u> thin film transistor, comprising:

- a substrate;
- a gate electrode disposed in the substrate, the gate electrode being made of metallic material;
 - a gate insulation layer disposed on the substrate and gate electrode;
 - a channel layer disposed on the gate insulation layer,
- a source ohmic contact layer and a drain ohmic contact layer arranged on opposite ends of the channel layer;
- a source electrode disposed on the substrate and source ohmic contact layer; and
- a drain electrode disposed on the substrate and drain ohmic contact layer.

Claim 2 (currently amended): The <u>single-gated</u> thin film transistor of claim 1, wherein the surface of the gate electrode is parallel with the surface of the substrate.

Claim 3 (canceled)

Claim 4 (currently amended): The single-gated thin film transistor of

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claim 1, wherein the gate electrode comprises Cu, Al, Ti, Mo, Cr, Ta, Nd or any alloy thereof.

Claim 5 (currently amended): The <u>single-gated</u> thin film transistor of claim 1, wherein a cross-section of the gate electrode is trapezoidal.

Claim 6 (currently amended): The <u>single-gated</u> thin film transistor of claim 1, wherein a cross-section of the gate electrode is rectangular.

Claim 7 (currently amended): The <u>single-gated</u> thin film transistor of claim 1, wherein the substrate is made of glass or silicon oxide.

Claim 8 (currently amended): The <u>single-gated</u> thin film transistor of claim 1, wherein the gate insulation layer is made of silicon nitride or silicon oxide.

Claim 9 (currently amended): The <u>single-gated</u> thin film transistor of claim 1, wherein the channel layer is made of amorphous silicon or polycrystalline silicon.

Claim 10 (currently amended): The <u>single-gated</u> thin film transistor of claim 9, wherein the source and drain ohmic contact layers are formed by doping the channel layer.

Claim 11 (currently amended): A display device including a plurality of <u>single-gated</u> thin film transistors used to control and drive display material, wherein each of the <u>single-gated</u> thin film transistors comprises:

a substrate;

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- a gate electrode disposed in the substrate, the gate electrode being made of metallic material;
 - a gate insulation layer disposed on the substrate and gate electrode;
 - a channel layer disposed on the gate insulation layer;
- a source ohmic contact layer and a drain ohmic contact layer arranged on the two sides of the channel layer;
- a source electrode disposed on the substrate and source ohmic contact layer; and
- a drain electrode disposed on the substrate and drain ohmic contact layer.

Claim 12 (original): The display device of claim 11, wherein the display material is liquid crystal.

Claims 13-20 (canceled)

Claim 21 (currently amended): A <u>single-gated</u> thin film transistor comprising:

- a substrate defining a cavity in an upper face thereof;
- a gate electrode filled in said cavity, the said gate electrode being made of metallic material;
- a gate insulation layer applied upon said substrate covering both said substrate and said gate electrode;
- a channel layer applied upon said gate insulation layer and only covering a central portion of an upper face of said gate insulation layer;
- a source electrode disposed upon one side of said channel layer and further covering a portion of said gate insulation layer wherein said portion is exposed to an exterior before said source electrode is applied thereto; and

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a drain electrode disposed upon the other side of the <u>said</u> channel layer and further covering another portion of said gate insulation layer wherein said another portion is exposed to the exterior before said drain electrode is applied thereto.